263787US26PCT Docket No.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

INVENTOR(S) Hiroshi MASHIMA, et al.

ART UNIT: 1792 SERIAL NO: 10/518,371

FILING DATE: December 28, 2004 EXAMINER: GAMBETTA, KELLY M.

METHOD FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION AND APPARATUS FOR FOR:

PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION

FEE TRANSMITTAL

No additional fee is required

Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.

The Fee has been calculated as shown below:

FOR	FOR NUMBER FILED		RATE	CALCULATIONS	
TOTAL CLAIMS	10 - 20 =	0	x \$52 =	\$0.00	
INDEPENDENT CLAIMS	1 - 3 =	0	x \$220 =	\$0.00	
☐ MULTIPLE DEPENDEN	\$0.00				
☐ LATE FILING OF DECL	\$0.00				
	\$0.00				
	\$0.00				
☐ REDUCTION BY 50% F	\$0.00				
☐ FILING IN NON-ENGLI	\$0.00				
			TOTAL	\$0.00	

Please charge	Deposit	Account No.	15-0030 in	the amount	of	\$0.00

- ☐ Credit card payment is being made online (if electronically filed), or is attached hereto (if paper filed), in the amount of \$0.00.
- The Director is hereby authorized to charge any additional fees which may be required for the papers being filed herewith and for which no payment is enclosed herewith, or credit any overpayment to Deposit Account No. 15-0030, with the EXCEPTION of deficiencies in fees for multiple dependent claims in new applications.
- If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030.

Submitted by:

Steven P. Weihrouch

Registration No. 32,829

Customer Number

Tel. (703) 413-3000 Fax. (703) 413-2220 (OSMMN 09/09)

Craig R. Feinberg Registration No. 62,116